

References

[1]. R. Miyazawa *et al.*, *Journal of Vacuum Science and Technology B*, **2024**, 42, 022213.

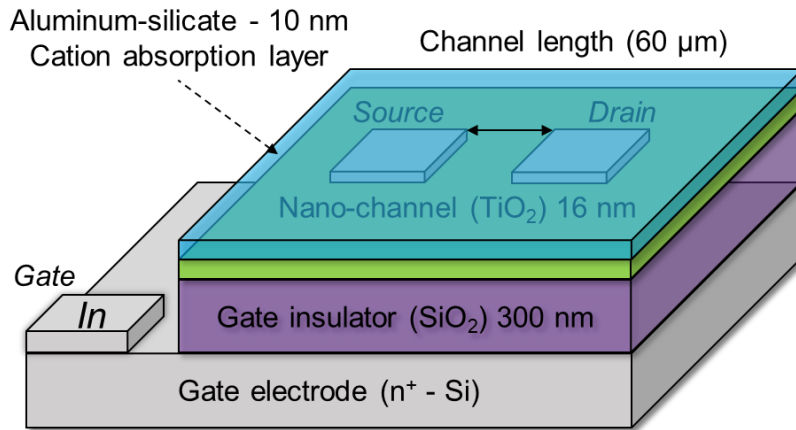


Fig.1 Schematic of TiO₂-TFT with aluminum-silicate and SiO₂ multiple films.

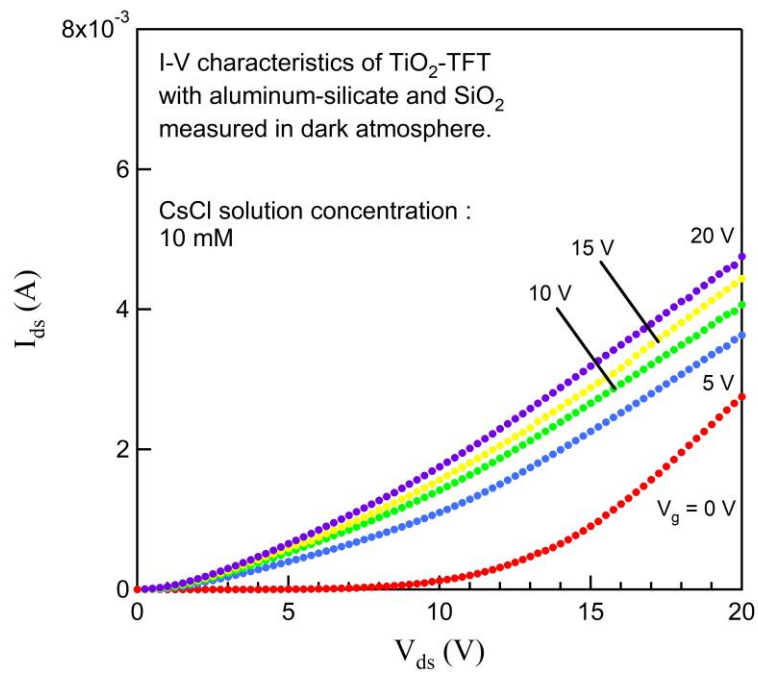


Fig.2 I-V characteristics of TiO₂-TFT after immersion CsCl solutions.

CsCl solution concentration: 10 mM